XP-1119 PATENT

## **ABSTRACT**

An illumination modulator correction system is disclosed for adjusting the operational parameters of an illumination modulator in an imaging system. The correction system includes a modulator pattern unit for providing a test pattern on the illumination modulator, a modulator adjustment unit for permitting an actuation voltage on the illumination modulator to be changed through a range of actuation voltage values, a detector for receiving a modulated illumination field from the illumination modulator, a sampling unit for determining at least one sample value for at least one area of the modulated illumination field, and an evaluation unit for determining a minimum sample value within the range of actuation voltage values of the illumination modulator.